



PATENT
2342-0111P

IN THE U.S. PATENT AND TRADEMARK OFFICE

APPLICANT: Kazuyuki TOYODA et al. CONF. NO.: 6177
APPL. NO.: 08/905,971 GROUP: 1763
FILED: August 5, 1997 EXAMINER: R. Zervig
FOR: SUBSTRATE PROCESSING APPARATUS

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AMENDMENT

Honorable Commissioner for Patents
Washington, D.C. 20231

February 27, 2003

Sir:

In response to the Office Action dated August 27, 2002, the period for response extended three (3) months to February 27, 2003 by the attached petition for extension of time, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please replace claims 1 and 14 with the following amended claims: Please note that claims 1 and 14 are presented below in their amended form. They are further presented as an Attachment to the Amendment whereby the amendments to the claims are outlined using the conventional method of bracketing and underlining.

1. (Three Times Amended) A substrate processing apparatus, comprising:
a substrate transfer section;
a plurality of modules, each of said plurality of modules being directly detachably attached to said substrate transfer section; and

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